

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Attn: APPLICATION BRANCH**
Hiroshi SOTOZAKI et al. : Attorney Docket No. 2004_0208
Serial No. NEW :
Filed February 10, 2004 :

METHOD AND APPARATUS FOR
POLISHING A SUBSTRATE
**(Rule 1.53(b) Continuation
of Serial No. 10/283,154,
Filed October 30, 2002, which is a divisional
of Serial No. 09/434,482, filed November 5, 1999)**

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

CLAIM OF PRIORITY UNDER 35 USC 119

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

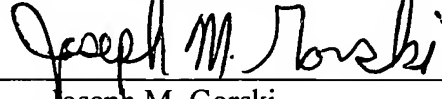
Sir:

Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 10-316522, filed November 6, 1998, Japanese Patent Application No. 11-138705, filed May 19, 1999 and Japanese Patent Application No. 11-236776, filed August 24, 1999, as acknowledged in the Declaration of this application.

Certified copies of said Japanese Patent Application are of record in grand-parent application Serial No. 09/434,482, filed November 5, 1999.

Respectfully submitted,

Hiroshi SOTOZAKI et al.

By 
Joseph M. Gorski
Registration No. 46,500
Attorney for Applicants

JMG/edg
Washington, D.C. 20006-1021
Telephone (202) 721-8200
Facsimile (202) 721-8250
February 10, 2004